



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Inventor application of: Hemker et al.

Attorney Docket No.: LAM1P128D1

Application No.: 10/618,289

Examiner: ANDERSON, MATTHEW A.

Filed: July 11, 2003

Group: 1765

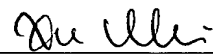
Title: MATERIALS AND GAS CHEMISTRIES  
FOR PROCESSING SYSTEMS

Confirmation No.: 4379

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on April 20, 2005 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

Signed: \_\_\_\_\_

  
Susan W. Xu

**INFORMATION DISCLOSURE STATEMENT  
BEFORE FINAL ACTION OR NOTICE OF ALLOWANCE  
(37 CFR §§ 1.56 AND 1.97(c))**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to examination of the above-identified patent application. Applicants submit the list of these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application. The above-identified application is a Divisional Application of prior application U.S. Patent Application No. 09/440,794. This prior application is being relied upon for an earlier filing date under 35 U.S.C. § 120. Because the listed references were either cited by the PTO, or submitted to the PTO in the prior application, under 37 CFR § 1.98(d) Applicants submit that copies need not be provided. Please note that references (marked with an \*) are enclosed herewith since these references were not cited during the prosecution of the above-mentioned application.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that this reference indeed constitutes prior art.

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This Information Disclosure Statement is being filed after the mailing date of the first Office Action on the merits, or after three months of the filing date of this application, whichever event occurred last, but it is believed before the mailing date of either: (i) a final action under §1.113 or (ii) a notice of allowance under §1.311, whichever occurs first.

Accompanying this Information Disclosure Statement is

☒ the fee set forth in 37 CFR 1.17(p).

If fees are due, enclosed is our Check No. 26104 for \$180.00 in payment of the Information Disclosure Statement Fee. If it is determined that any additional fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. LAM1P128D1).

Respectfully submitted,  
BEYER WEAVER & THOMAS, LLP

  
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<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. LAM1P128D1	Application No.: 10/618,289
	Applicant: Hemker et al. Filing Date July 11, 2003	Group 1765

**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
	A1	4,948,458	08/14/90	Ogle			08/14/89
	A2	4,990,229	02/05/91	Campbell et al.			06/13/89
	A3	5,091,049	02/25/92	Campbell et al.			06/29/90
	A4	5,122,251	06/16/92	Campbell et al.			02/04/91
	A5	5,421,891	06/06/95	Campbell et al.			10/19/92
	A6	5,429,070	07/04/95	Campbell et al.			11/20/92
	A7	5,587,038	12/24/96	Cecchi et al.			06/16/94
	A9	5,810,932	09/22/98	Ueda et al.			08/05/96
	A10*	5,021,114	06/04/91	Saito et al.			07/19/88
	A11*	5,032,205	07/16/91	Hershkowitz et al.			05/05/89
	A12*	5,226,967	07/13/93	Chen et al.			05/14/92
	A13*	5,401,350	03/28/95	Patrick et al.			03/08/93
	A14*	5,540,800	07/30/96	Qian			06/23/94
	A15*	5,587,205	12/24/96	Saito et al.			12/23/93
	A16*	5,669,975	09/23/97	Ashtiani			03/27/96
	A17*	5,811,022	09/22/98	Savas et al.			11/15/94
	A18*	6,030,486	02/29/00	Loewenhardt et al.			12/16/96
	A19*	6,096,160	08/01/00	Kadomura			04/16/97
Examiner				Date Considered			

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No.	Application No.:
	LAM1P128D1	10/618,289
	Applicant:	
	Hemker et al.	
	Filing Date	Group
	July 11, 2003	1765

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
							Yes	No
	B1	EP 0838843 A2	04/29/98	EPO				
	B2	EP 0821397 A2	01/28/98	EPO				
	B3	WO 99/50866	10/07/99	PCT				
	B4*	05267237	10/15/93	EP				
	B5*	09139380	05/27/96	EP				
	B6*	2231197	11/07/90	GB				
	B7*	4-329875	11/08/92	JP.				

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	C1	Japanese Application No. 04094953, filed March 1992, entitled "PLASMA DAMAGE REDUCTION AND PLASMA PROCESSOR, by Minegishi Kazushige, Patent Abstracts of Japan, Vol. 18, No. 33.
	C2	Japanese Application No. 08255259, filed August 1996, entitled "PLASMA DAMAGE REDUCTION AND PLASMA PROCESSOR, by Minegishi Kazushige, Patent Abstracts of Japan, Vol. 18, No. 33.
	C3*	Office Action dated March 28, 2001 for U.S. Application No. 09/439,661, entitled "PLASMA PROCESSING SYSTEMS," filed on November 15, 1999, now U.S. Patent No. 6,341,574 B1.
	C4*	Office Action dated June 27, 2001 for U.S. Application No. 09/439,661, entitled "PLASMA PROCESSING SYSTEMS," filed on November 15, 1999, now U.S. Patent No. 6,341,574 B1.
Examiner		Date Considered

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.